

A method of selectively laser patterning thin layers to form flexible implantable devices

Patterning method for manufacturing implantable thin film devices.

Applications: Implantable devices for stimulation



Features	Benefits
1-2 μ m precision	Allows for patterning of very thin layers without damage caused adjacent layers. For example, removal of resistant polymer materials from on top of more susceptible thin metal films, or creation of microfluidic channels
Fabrication out of 2D plane	So curved surfaces or 3D structures can be patterned
No requirement for toxic chemicals	Making the process less hazardous for the operator and better for the environment
Rapid processing	Easy to implement design changes and prototype multiple versions that previous would have required separately manufactured masks

Awaiting patent and Available for

- Co-development
- Consulting
- Licensing

To find out more, contact enquiries@innovation.ox.ac.uk and quote the project number.

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